



# Custom Built Hollow Cathode Plasma Sources

Meaglow Ltd offers custom built hollow cathode plasma sources for semiconductor growth and processing. Meaglow offers the following with it's hollow cathode sources:

- **Reduced oxygen contamination**
- ALD system conversions
- Experience with LP-MOCVD conversion
- Scalable to large areas (more holes = greater area)
- No dielectric windows (which can act as sources of contamination)
- High electron density – similar to inductively coupled and microwave plasma sources
- Wide range of operating pressures (eg. from < 100 mTorr to > 5 Torr).
- RF or DC operation, oxygen, nitrogen, ammonia, hydrogen, nitrous oxide, argon, flourine, chlorine, other gases.

## Related Papers:

- K. S. A. Butcher, B. W. Kemp, I. B. Hristov, P. Terziyska, P. W. Binsted and D. Alexandrov, Japanese Journal of Applied Physics **51** (2012) 01AF02.
- C. Ozgit-Akgun, E. Goldenberg, A. Kemal Okyay and N. Biyikili, Journal of Materials Chemisty C **2** (2014) 2123.
- K. S.A. Butcher, V. Georgiev and D. Georgieva, Coatings **11** (2021) 1506.

For more information on Meaglow Ltd or its hollow cathode plasma sources, visit our website [www.meaglow.com](http://www.meaglow.com) or contact us at [info@meaglow.com](mailto:info@meaglow.com).

